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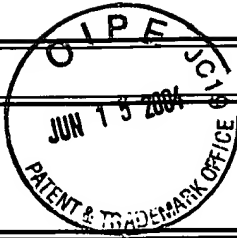
Electronic Filing System (EFS) Data  
Electronic Patent Application Submission  
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EFS ID: 62626  
Application ID: 09912844  
Title of Invention: HIGH PRESSURE PROCESSING CHAMBER  
FOR SEMICONDUCTOR SUBSTRATE  
First Named Inventor: Maximilian Biberger  
Domestic/Foreign Application: Domestic Application  
Filing Date: 2001-07-24  
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Submission Type: Information Disclosure Statement  
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Confirmation number: 5915  
Attorney Docket Number: NONE



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Electronic Version v1.1  
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## Title of Invention

HIGH PRESSURE PROCESSING CHAMBER FOR SEMICONDUCTOR  
SUBSTRATE

Application Number: 09/912844  
Date: 2001-07-24  
First Named Applicant: Maximilian A. Biberger  
  
Confirmation Number: 5915  
Attorney Docket Number:



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Thomas B. Haverstock Registered Number: 32571	/tbh/	Attorney

Documents being submitted  
us-ids

Files  
SSI00501-usidst.xml  
us-ids.dtd  
us-ids.xsl

Comments

# ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of Invention

## HIGH PRESSURE PROCESSING CHAMBER FOR SEMICONDUCTOR SUBSTRATE

Application Number: 09/912844

Confirmation Number: 5915

First Named Applicant: Maximilian Bibberger

Attorney Docket Number:

Search string: ( 5186594 or 5769588 or 5906866 or 5975492 or 6122566 or 6355072 or 6454519 ).pn.



**Certification:** This Information Disclosure Statement was submitted under the following conditions, which satisfies the requirement under 37 CFR 1.97(e). The filer certified:

That no item of information contained in the information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application, and, to the knowledge of the person signing the certification after making reasonable inquiry, no item of information contained in the information disclosure statement was known to any individual designated in 37 CFR 1.56(c) more than three months prior to the filing of the information disclosure statement.

### US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
	1	5186594	1993-02-16	Toshima et al.			
	2	5769588	1998-06-23	Toshima et al.			
	3	5906866	1999-05-25	Webb			
	4	5975492	1999-11-02	Brenes			
	5	6122566	2000-09-19	Nguyen et al.			
	6	6355072	2002-03-12	Racette et al.	B1		
	7	6454519	2002-09-24	Toshima et al.	B1		

### Signature

Examiner Name	Date